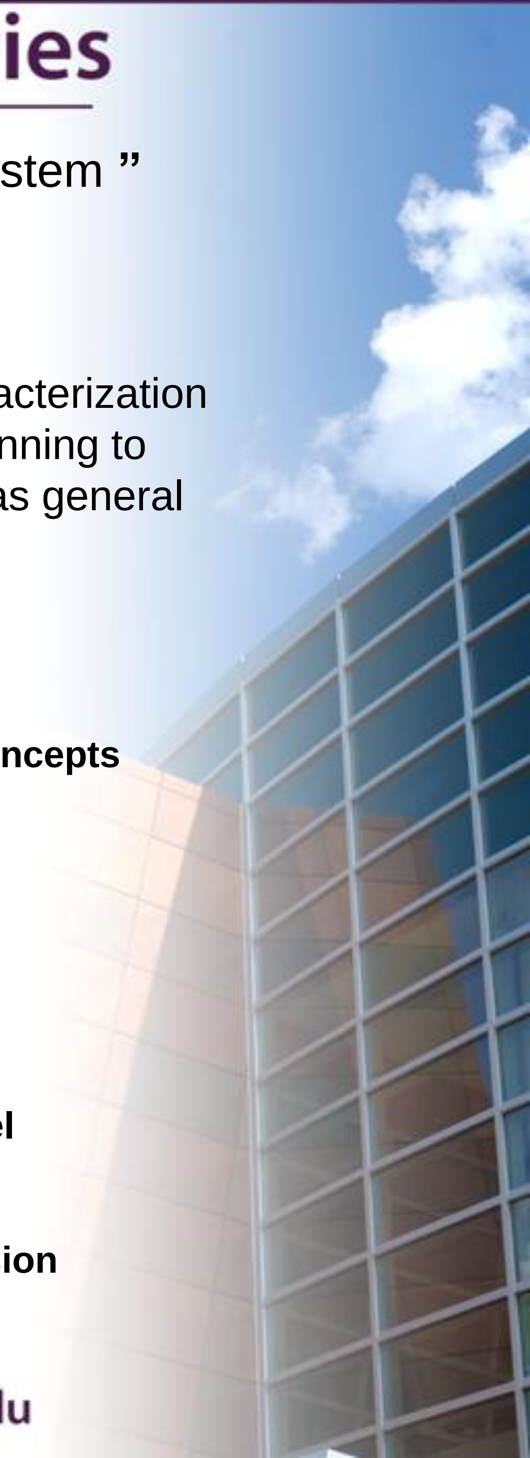
BIRCK Nanotechnology Center

PURDUE UNIVERSITY Discovery Park

Nanotechnology Seminar Series



"Keithley 4200-SCS Semiconductor Characterization System "

November 10 & 11, 2010
BNC, ROOM 2001, 8:00 - 5:00

This training session is based on the Keithley 4200-SCS Semiconductor Characterization System which has recently been purchased by Birck. It is intended for beginning to intermediate users. It covers basic concepts, both of the instrument, as well as general measurement considerations.

Agenda

Nov 10

8:00 - 9:00 am Introduction, System Overview: System Architecture, Hardware Features, and Software Features, Source-Measure Features and Concepts
9:15 - 11:00 am Basic *KITE* (Keithley Interactive Test Environment)
12:30 - 1:30 pm KITE Set-up and Features, Speed, timing and noise settings
1:45 - 3:00 pm General shielding, noise and guarding, Low Current and High Resistance Measurement Techniques
3:30 - 5:00 pm Troubleshooting instrument and results
Measurement Tools and Considerations

Nov 11

8:00 - 9:00 am Keithley CONfiguration Utility (*KCON*) Overview, Basic *KULT* (low level programming) , Basic *KXCI (Keithley External Command Interface)*
9:15 - 11:00 am CVU Overview
12:30 - 5:00 pm Hardware and Connections , Projects and Applications/Hands-on session

(Host: Aamer Mahmood, amahmood@purdue.edu, 46697)

PURDUE UNIVERSITY NSAC

NCN nanoHUB.org

PRISM

PURDUE ENGINEERING Think impact.

nano.purdue.edu